



SHEET 1 OF 2

FORM PTO - 1449 INFORMATION DISCLOSURE STATEMENT	ATTORNEY DOCKET NO.: IBX-009 APPLICANT(S): Cao et al. SERIAL NO.: 10/801,064 FILING DATE: March 15, 2004 GROUP: Not yet assigned
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U.S. PATENT DOCUMENTS

EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
all	A1	5,467,883	11/21/95	Frye et al.	216	60	11/27/93
	A2	5,559,690	9/24/96	Keeler et al.	364	164	9/16/94
	A3	5,654,903	8/5/97	Reitman et al.	364	551.01	11/7/95
	A4	5,740,033	4/14/98	Wassick et al.	364	149	10/13/92
	A5	6,268,226	7/31/01	Angell et al.	438	16	6/30/99

FOREIGN PATENT DOCUMENTS

EXAM. INIT.		DOCUMENT NUMBER	DATE	COUNTRY CODE	CLASS	SUB CLASS	FILING DATE	ABSTRACT ONLY	ENGLISH LANG (Y/N)
all	B1	WO 01/57605	8/9/01	WO	G05B	13/04	1/11/01	N	Y
all	B2	DE196 37 917 A1	3/19/98	DE	G05B	13/04	9/17/96	Y	

OTHER ART, JOURNAL ARTICLES, ETC.

EXAM. INIT.	OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)
all	C1 Card et al., "Dynamic Neural Control for Plasma Etch Process," <u>IEEE Transactions on Neural Networks</u> , (1997).
	C2 Card et al., "Impacts of Maintenance Input on the Prediction Accuracy of an APC Controller," Presentation at AEC/APC Symposium XIV (September 9-11, 2002).
	C3 Card et al., "Advanced Analysis of Dynamic Neural Control Advisories for Process Optimization and Parts Maintenance," Presentation at AEC/APC Symposium XIV (September 9-11, 2002).
	C4 Dillon et al., "Guest Editorial Everyday Applications of Neural Networks," <u>IEEE Transactions on Neural Networks</u> , 8:4 (July 1997).
	C5 Hatzipantelis et al., "Comparing Hidden Markov Models with Artificial Neural Network Architectures for Condition Monitoring Applications," <u>Artificial Neural Networks</u> , 26-28, Conference Publication No. 409 (June 1995).

af	C6	Kim et al., "Intelligent Control of Via Formation by Photosensitive BCB for MCM-L/D Applications," <u>IEEE Transactions on Semiconductor Manufacturing</u> , 12:503 (1999).
	C7	Konstantopoulos et al., "Controllers with Diagnostic Capabilities. A Neural Network Implementation. Journal of Intelligent and Robotic Systems," Department of Electrical Engineering, University of Notre Dame, IN 12: 197-228 (1995).
	C8	Moyne, "AEC/APC Vision: A Research and Suppliers' Point of View," 3 rd Annual European AEC/APC Conference Proceedings (2002).
	C9	Rietman et al., "A Study on $\mathcal{R}^m \rightarrow \mathcal{R}^1$ Maps: Application to a 0.16- μ m Via Etch Process Endpoint," <u>IEEE</u> (2000).
	C10	Rietman et al., "A System Model for Feedback Control and Analysis of Yield: A Multistep Process Model of Effective Gate Length, Poly Line Width, and IV Parameters", <u>IEEE</u> (2001).
	C11	Rietman, "Neural Networks in Plasma Processing," <u>Journal of Vacuum Science and Technology: Part B, IEEE Transactions on Semiconductor Manufacturing</u> , 14:1 (2001).
	C12	Smyth et. al., "Hidden Markov Models an Neural Networks for Fault detection in Dynamic Systems," California Institute of Technology (1993).
✓	C13	Zhang et al, "Control of Spatial Uniformity in Microelectronics Manufacturing: An Integrated Approach," Proceedings of AEC/APC (2000).
EXAMINER <i>Edward Raymond</i> DATE CONSIDERED <i>6/24/05</i>		